The listing of claims will replace all prior versions, and listings, of claims in the application:

Listing of Claims:

- 1.-6. (Canceled)
- 7. (Currently Amended) A driver circuit comprising:
- a shift register;
- a buffer circuit electrically connected to the shift register, comprising a source follower circuit comprising [[a]] an n-channel thin film transistor; and
 - an analog memory electrically connected to the buffer circuit,

wherein:

a channel forming region of the <u>n-channel</u> thin film transistor comprises a polycrystalline semiconductor,

the <u>n-channel</u> thin film transistor is a depletion mode transistor, [[and]]

an impurity is doped to a channel forming region of a semiconductor layer of the <u>n-channel</u> thin film transistor at a concentration of 5×10^{12} to <u>not greater than</u> 5×10^{14} atoms/cm², and

as for the impurity, phosphorous is used to the n-channel thin film transistor.

- 8. (Currently Amended) The driver circuit according to claim 7, wherein the <u>n-channel</u> thin film transistor is directly connected to an output terminal.
- 9. (Original) The driver circuit according to claim 7, wherein the polycrystalline semiconductor film is provided over either a quartz substrate or a glass substrate.

10. (Currently Amended) A driver circuit comprising:

a shift register;

a buffer circuit electrically connected to the shift register, comprising a source follower circuit comprising [[a]] an n-channel thin film transistor; and

an analog memory electrically connected to the buffer circuit,

wherein:

a channel forming region of the n-channel thin film transistor comprises a polycrystalline semiconductor which is formed by crystallizing an amorphous silicon,

the n-channel thin film transistor is a depletion mode transistor, [[and]]

an impurity is doped to a channel forming region of a semiconductor layer of the <u>n-channel</u> thin film transistor at a concentration of 5×10^{12} to not greater than 5×10^{14} atoms/cm², and

as for the impurity, phosphorous is used to the n-channel thin film transistor.

- 11. (Currently Amended) The driver circuit according to claim 10, wherein the n-channel thin film transistor is directly connected to an output terminal.
- 12. (Original) The driver circuit according to claim 10, wherein the polycrystalline semiconductor film is provided over either a quartz substrate or a glass substrate.
 - 13. (Currently Amended) A driver circuit comprising: a shift register;
- a buffer circuit electrically connected to the shift register, comprising a bootstrap circuit comprising [[a]] an n-channel thin film transistor; and

an analog memory electrically connected to the buffer circuit,

wherein:

a channel forming region of the <u>n-channel</u> thin film transistor comprises a polycrystalline semiconductor,

the <u>n-channel</u> thin film transistor is a depletion mode transistor, [[and]]

an impurity is doped to a channel forming region of a semiconductor layer of the <u>n-channel</u> thin film transistor at a concentration of 5×10^{12} to <u>not greater than</u> 5×10^{14} atoms/cm², and

as for the impurity, phosphorous is used to the n-channel thin film transistor.

- 14. (Currently Amended) The driver circuit according to claim 13, wherein the <u>n-channel</u> thin film transistor is directly connected to an output terminal.
- 15. (Original) The driver circuit according to claim 13, wherein the polycrystalline semiconductor film is provided over either a quartz substrate or a glass substrate.
 - 16. (Currently Amended) A driver circuit comprising:
 - a shift register;
- a buffer circuit electrically connected to the shift register, comprising a bootstrap circuit comprising [[a]] an n-channel thin film transistor; and

an analog memory electrically connected to the buffer circuit, wherein:

a channel forming region of the <u>n-channel</u> thin film transistor comprises a polycrystalline semiconductor which is formed by crystallizing an amorphous silicon,

the <u>n-channel</u> thin film transistor is a depletion mode transistor, [[and]]

an impurity is doped to a channel forming region of a semiconductor layer of the n-channel thin film transistor at a concentration of 5 x 10¹² to not greater than 5 x 10¹⁴ atoms/cm², and

as for the impurity, phosphorous is used to the n-channel thin film transistor.

- 17. (Currently Amended) The driver circuit according to claim 16, wherein the n-channel thin film transistor is directly connected to an output terminal.
- 18. (Original) The driver circuit according to claim 16, wherein the polycrystalline semiconductor film is provided over either a quartz substrate or a glass substrate.

19.-24. (Canceled)

- 25. (Currently Amended) The driver circuit according to claim 7, wherein the semiconductor layer of the n-channel thin film transistor comprises a metal element which is capable of promoting the crystallization of a semiconductor film.
- 26. (Currently Amended) The driver circuit according to claim 10, wherein the semiconductor layer of the n-channel thin film transistor comprises a metal element which is capable of promoting the crystallization of a semiconductor film.
- 27. (Currently Amended) The driver circuit according to claim 13, wherein the semiconductor layer of the n-channel thin film transistor comprises a metal element which is capable of promoting the crystallization of a semiconductor film.

- 28. (Currently Amended) The driver circuit according to claim 16, wherein the semiconductor layer of the <u>n-channel</u> thin film transistor comprises a metal element which is capable of promoting the crystallization of a semiconductor film.
- 29. (Previously Presented) The driver circuit according to claim 25, wherein the metal element is nickel.
- 30. (Previously Presented) The driver circuit according to claim 26, wherein the metal element is nickel.
- 31. (Previously Presented) The driver circuit according to claim 27, wherein the metal element is nickel.
- 32. (Previously Presented) The driver circuit according to claim 28, wherein the metal element is nickel.
 - 33. (New) A driver circuit comprising:
 - a shift register;
- a buffer circuit electrically connected to the shift register, comprising a source follower circuit comprising a p-channel thin film transistor; and

an analog memory electrically connected to the buffer circuit,

wherein:

a channel forming region of the p-channel thin film transistor comprises a polycrystalline semiconductor,

the p-channel thin film transistor is a depletion mode transistor,

an impurity is doped to a channel forming region of a semiconductor layer of the p-channel thin film transistor at a concentration not greater than 5×10^{14} atoms/cm², and

as for the impurity, boron is used to the p-channel thin film transistor.

34. (New) The driver circuit according to claim 33,

wherein the p-channel thin film transistor is directly connected to an output terminal.

35. (New) The driver circuit according to claim 33,

wherein the polycrystalline semiconductor film is provided over either a quartz substrate or a glass substrate.

- 36. (New) A driver circuit comprising:
- a shift register;
- a buffer circuit electrically connected to the shift register, comprising a source follower circuit comprising a p-channel thin film transistor; and

an analog memory electrically connected to the buffer circuit,

wherein:

a channel forming region of the p-channel thin film transistor comprises a polycrystalline semiconductor which is formed by crystallizing an amorphous silicon,

the p-channel thin film transistor is a depletion mode transistor,

an impurity is doped to a channel forming region of a semiconductor layer of the p-channel thin film transistor at a concentration not greater than 5×10^{14} atoms/cm², and

as for the impurity, boron is used to the p-channel thin film transistor.

37. (New) The driver circuit according to claim 36,

wherein the p-channel thin film transistor is directly connected to an output terminal.

38. (New) The driver circuit according to claim 36,

wherein the polycrystalline semiconductor film is provided over either a quartz substrate or a glass substrate.

39. (New) A driver circuit comprising:

a shift register;

a buffer circuit electrically connected to the shift register, comprising a bootstrap circuit comprising a p-channel thin film transistor; and

an analog memory electrically connected to the buffer circuit,

wherein:

a channel forming region of the p-channel thin film transistor comprises a polycrystalline semiconductor,

the p-channel thin film transistor is a depletion mode transistor,

an impurity is doped to a channel forming region of a semiconductor layer of the p-channel thin film transistor at a concentration not greater than 5×10^{14} atoms/cm², and

as for the impurity, boron is used to the p-channel thin film transistor.

40. (New) The driver circuit according to claim 39,

wherein the p-channel thin film transistor is directly connected to an output terminal.

41. (New) The driver circuit according to claim 39,

wherein the polycrystalline semiconductor film is provided over either a quartz substrate or a glass substrate.

42. (New) A driver circuit comprising:

a shift register;

a buffer circuit electrically connected to the shift register, comprising a bootstrap circuit comprising a p-channel thin film transistor; and

an analog memory electrically connected to the buffer circuit, wherein:

a channel forming region of the p-channel thin film transistor comprises a polycrystalline semiconductor which is formed by crystallizing an amorphous silicon,

the p-channel thin film transistor is a depletion mode transistor,

an impurity is doped to a channel forming region of a semiconductor layer of the p-channel thin film transistor at a concentration not greater than 5×10^{14} atoms/cm², and

as for the impurity, boron is used to the p-channel thin film transistor.

43. (New) The driver circuit according to claim 42, wherein the p-channel thin film transistor is directly connected to an output terminal.

44. (New) The driver circuit according to claim 42,

wherein the polycrystalline semiconductor film is provided over either a quartz substrate or a glass substrate.

- 45. (New) The driver circuit according to claim 33, wherein the semiconductor layer of the p-channel thin film transistor comprises a metal element which is capable of promoting the crystallization of a semiconductor film.
- 46. (New) The driver circuit according to claim 36, wherein the semiconductor layer of the p-channel thin film transistor comprises a metal element which is capable of promoting the crystallization of a semiconductor film.

- 47. (New) The driver circuit according to claim 39, wherein the semiconductor layer of the p-channel thin film transistor comprises a metal element which is capable of promoting the crystallization of a semiconductor film.
- 48. (New) The driver circuit according to claim 42, wherein the semiconductor layer of the p-channel thin film transistor comprises a metal element which is capable of promoting the crystallization of a semiconductor film.
- 49. (New) The driver circuit according to claim 45, wherein the metal element is nickel.
- 50. (New) The driver circuit according to claim 46, wherein the metal element is nickel.
- 51. (New) The driver circuit according to claim 47, wherein the metal element is nickel.
- 52. (New) The driver circuit according to claim 48, wherein the metal element is nickel.